

2-27-03
XA-9631
PATENT APPLICATION

1c971 U.S. PTO
10/083503
02/27/02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

Hisao YAMAGATA et al.

Appln. No.:

Filed: HERewith

For: SEMICONDUCTOR DEVICE MANUFACTURING METHOD AND
SEMICONDUCTOR DEVICE SORTING SYSTEM TO BE USED
WITH THE SAME

* * *

INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Pursuant to 37 C.F.R. § 1.56, and without any
assertion as to materiality or prior art effect, the
documents listed on the attached Form PTO-1449 are hereby
cited.

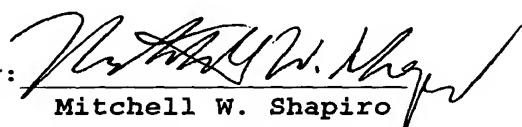
The Japanese documents on the attached list are
accompanied by English abstracts. Note also that Document
AL is cited in the specification on pages 1 and 29.

Respectfully submitted,

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By:


Mitchell W. Shapiro
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February 27, 2002

FORM PTO-1449				Atty. Docket No. XA-9631		Appln. No.	
LIST OF DOCUMENTS CITED BY APPLICANT				Applicant Hisao YAMAGATA et al.			
				Filing Date HEREWITH		Group	
U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
FOREIGN PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
	AL	✓ 8-86833	04/02/96	Japan			Abstract
	AM	✓ 9-64261	03/07/97	Japan			Abstract
	AN	✓ 9-64260	03/07/97	Japan			Abstract
	AO	✓ 58-121636	07/20/83	Japan			Abstract
	AP						
	AQ						
OTHER (including author, title, date, pertinent pages, etc.)							
	AR						
	AS						
	AT						
Examiner				Date Considered			
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.							

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10/08/93

02/27/02